IN THE CLAIMS:

1. (Original) A MEM apparatus comprising:

a substrate;

a first structure supported on said substrate;

an electrostatic component disposed between said substrate and said first structure and extending across an area of said substrate; and

at least one support structure disposed within said area of said substrate for supporting said first structure.

2. (Original) A MEM apparatus as set forth in Claim 1, wherein said electrostatic component comprises a movable electrode.

3. (Original) A MEM apparatus as set forth in Claim 1, wherein said electrostatic component comprises a static electrode.

4. (Original) A MEM apparatus as set forth in Claim 1, wherein said electrostatic component includes a movable electrode and a static electrode.

5. (Original) A MEM apparatus as set forth in Claim 4, wherein said support structure is positioned proximate to said static electrode.

6. (Original) A MEM apparatus as set forth in Claim 1, wherein said support structure has a height, relative to an axis extending between said first structure and said substrate, greater than a height of said electrostatic component, wherein said support structure maintains a separation between said first structure and said electrostatic component.

7. (Original) A MEM apparatus as set forth in Claim 1, wherein said at least one support structure comprises multiple support structures distributed across an area of said first structure.

8. (Original) A MEM apparatus as set forth in Claim 1, wherein said support structure is substantially electrically isolated from said electrostatic component.

9. (Currently Amended) ~~An~~ A MEM apparatus as set forth in Claim 1, wherein said electrostatic element comprises a movable element that is movable across a range of positions and said support structure is positioned to avoid mechanical interference with said movable element as said movable element moves across said range of positions.

10. (Original) A MEM apparatus comprising:

a substrate;

a first structure supported on said substrate;

a movable component disposed between said substrate and said first structure and extending across an area of said substrate; and

at least one support structure disposed within said area of said substrate for supporting said first structure.

11. (Original) A MEM apparatus as set forth in Claim 10, wherein said movable component includes a movable electrode and a static electrode and said support structure is positioned proximate to said static electrode.

12. (Original) A MEM apparatus as set forth in Claim 10, wherein said support structure has a height, relative to an axis extending between said first structure and said substrate, greater than a height of said movable component, wherein said support structure maintains a separation between said first structure and said movable component.

13. (Original) A MEM apparatus as set forth in Claim 10, wherein said at least one support structure comprises multiple support structures distributed across an area of said first structure.

14. (Original) A MEM apparatus as set forth in Claim 10, wherein said support structure is substantially electrically isolated from said movable component.

15. (Original) An MEM apparatus as set forth in Claim 10, wherein said movable component is movable across a range of positions and said support structure is positioned to avoid mechanical interference with said movable component as said movable component moves across said range of

positions.

16. (Original) A MEM apparatus, comprising:

a movable optical component;

an actuator mechanism for effecting movement of said optical component;

a cover extending over at least a portion of said actuator mechanism, said cover further extending across an area; and

at least one support structure, disposed within said area, for supporting said cover.

17. (Original) A MEM apparatus as set forth in Claim 16 wherein said actuator mechanism comprises a movable electrode and a static electrode and said support structure is positioned proximate to said static electrode.

18. (Original) A MEM apparatus as set forth in Claim 16, wherein said support structure has a height, relative to an axis extending between said cover and a bottom surface of said actuator mechanism, greater than a height of said actuator mechanism, wherein said support structure maintains a separation between said cover and said actuator mechanism.

19. (Original) A MEM apparatus as set forth in Claim 16, wherein said at least one support structure comprises multiple support structures distributed across an area of said cover.

20. (Original) A MEM apparatus as set forth in Claim 16, wherein said support structure is substantially electrically isolated from said actuator mechanism.

21. (Original) An MEM apparatus as set forth in Claim 16, wherein said actuator mechanism comprises a movable component that is movable across a range of positions and said support structure is positioned to avoid mechanical interference with said movable component as said movable component moves across said range of positions.

22. (Original) A MEM apparatus, comprising:

a substrate; and

a micromachined structure formed on said substrate including:

an electrical lead supported on said substrate; and

filter structure, supported on said substrate, for filtering an undesired electrical component from said lead.

23. (Original) An apparatus as set forth in Claim 22, wherein said filter comprises structure for establishing a capacitance between said structure and said electrical lead.

24. – 29. Cancelled

Respectfully submitted,

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